

- [9] 2015/10/24@Hangzhou in China
The 16th International Manufacturing Conference in China (IMCC2015)
Plasma-assisted polishing: Novel damage-free atomically flat finishing technique for wide gap semiconductor materials
○K. Yamamura
- [8] 2015/10/06@Jeju in Korea
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Study on removal mechanism of sapphire in plasma assisted polishing
○C. Kageyama, K. Monna, H. Deng, K. Endo, K. Yamamura
- [7] 2015/09/29@ILL- Grenoble in France
4th International Workshop on Neutron Delivery Systems
Development of a Neutron Microscope using Wolter Supermirrors
○K. Soyama, H. Hayashida, D. Yamazaki, R. Maruyama, Y. Goto, K. Yamamura
- [6] 2015/08/25@Cape Town in South Africa
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Plasma-assisted polishing of gallium nitride to obtain a pit-free and atomically flat surface
○H. Deng, K. Endo, K. Yamamura
- [5] 2015/08/18@Harbin in China
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Planarization and Smoothing of CVD Grown Diamond Wafer by Atmospheric Pressure Plasma Based Process
○H. Dojo, T. Tabata, K. Endo, H. Yamada , A. Chyayahara , Y. Mokuno, K. Yamamura
- [4] 2015/08/18@Harbin in China
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Improvement of Form Accuracy in NC-PCVM by Compensation of Surface Temperature Change
○S. Sakaiya, K. Endo, K. Yamamura
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○K. Yamamura, K. Hosoya, Y. Imanishi, H. Deng, K. Endo

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Polishing characteristics of CVD-SiC in plasma-assisted polishing
O.H. Deng, K. Endo, K. Yamamura
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